

200 Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-1035-	SERIAL NO. 09/234,233
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Weimin Li	
				FILING DATE January 20, 1999	GROUP 2818

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NOV 23 2001  
PATENT & TRADEMARK OFFICE

U.S. PATENT DOCUMENTS						
*Exam Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
DV	AA	5,801,399	Hattori et al	257	69	
DV	AB	5,994,730	Shrivastava et al	257	306	
DV	AC	6,040,619	Wang et al	257	649	
DV	AD	6,060,765	Maeda	257	635	
DV	AE	6,060,766	Mehta et al	257	639	
DV	AF	6,133,613	Yao et al	257	437	
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FOREIGN PATENT DOCUMENTS							
	Document Number	Date	Country	Class	Subclass	Translation	
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OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)		
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EXAMINER <i>Gruland</i>	DATE CONSIDERED 02/12/02
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		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M22-1035		SERIAL NO. 09/234,233	
FIRST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Weimin Li			
				FILING DATE January 20, 1999		GROUP 2818	
U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
DV	AA	5,482,894	01-1996	Havemann			
DV	AB	4,552,783	11-1985	Stoll et al			
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OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
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EXAMINER <i>Phil</i>				DATE CONSIDERED 08/22/02			
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							

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200-Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M22-1035		SERIAL NO. 09/234,732	
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				FILING DATE January 20, 1999		GROUP 2818	
U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate
DV	AA	6,204,168	03/2001	Nak et al			
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FOREIGN PATENT DOCUMENTS							
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OTHER REFERENCES (Including Author, Title, Date, Portion: Pages, Etc.)							
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EXAMINER <i>ghedani</i>				DATE CONSIDERED 08/12/03			
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with OCA communication to applicant.							

200 Form PCT <b>U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE</b>		ATTY. DOCKET NO. M22-1035		SERIAL NO. 09/234,233	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Weimin Li	
FILING DATE January 20, 1999				GROUP 2818	

U.S. PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
DV	AA	5,986,318	11/1999	Kim et al			
DV	AB	6,087,064	06/2000	Lin et al			
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FOREIGN PATENT DOCUMENTS							
Document Number	Date	Country	Class	Subclass	Translation		
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OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)			
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EXAMINER <i>Shuland</i>	DATE CONSIDERED <i>05/27/03</i>
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200 Form PCT/44 <b>U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE</b>		ATTY. DOCKET NO. M122-1035		SERIAL NO. 09/234,233	
<b>LIST OF ART CITED BY APPLICANT</b> (Use several sheets if necessary)				APPLICANT Weimin Li	
FILING DATE January 20, 1999				GROUP 2818	

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U.S. PATENT DOCUMENTS							
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DV	AA	5,986,318	11/1999	Kim et al			
DV	AB	6,087,064	06/2000	Lin et al			
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	AE						
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FOREIGN PATENT DOCUMENTS							
	Document Number	Date	Country	Class	Subclass	Translation	
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OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)			
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EXAMINER <i>Shuland</i>	DATE CONSIDERED <i>05/27/03</i>
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LIST OF ART CITED BY APPLICANT  
(Use several sheets if necessary)APPLICANT  
Weidun Li et alFILING DATE  
January 20, 1999GROUP  
2118

## U.S. PATENT DOCUMENTS

Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
DV	AA 4,775,478	07/1988	Abernathy et al			
	AB 4,870,470	09/1989	Bae et al			
	AC 5,312,768	05/1994	Gonzalez			
	AD 5,459,838	08/1995	Yang			
	AE 6,001,747	12/1999	Aznapragada			
	AF 6,518,122	02/2003	Chan			
	AG 6,492,688	12/2002	Ng			
	AH 6,375,114	04/2002	Jung			
DV	AJ 2001/0019868	09/2001	Gonzalez et al			
	AK					
	AL					

## FOREIGN PATENT DOCUMENTS

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	AO							
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## OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

DV	AR	Wells, S., "Silicon Processing for the VLSI Era." Vol. 1, pp. 189-190.
	AS	
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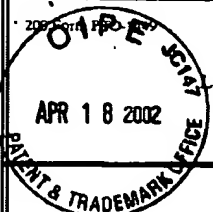
\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 600; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
DV	AA	5,498,555	03/96	Lin				
DV	AB	6,153,504	11-00	Shields et al.				
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FOREIGN PATENT DOCUMENTS								
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DV	AM	7201716	08/95	Japan			x	
DV	AN	8046186	02/96	Japan			x	
DV	AO	10-163083	06/98	Japan				
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)								
DV	AP		Wolf, S., Silicon Process., Vol 2 48-49 and 435					
	AO							
	AR							
EXAMINER <i>ghulani</i>				DATE CONSIDERED 06/17/04				
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								

200 Form PTO-1419		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-1035	SERIAL NO. 09/234,233	
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				FILING DATE January 20, 1999		GROUP 2818
U.S. PATENT DOCUMENTS						
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
DV	AA	6,004,850	12/99	Lucas		
	AB	6,140,677	10/00	Gardner		
	AC	6,133,096	10/00	Su		
	AD	6,136,636	10/00	Wu		
	AE	5,933,721	8/99	Hause		
	AF	5,981,368	11/99	Gardner		
	AG	6,159,804	12/00	Gardner		
	AH	6,130,168	10/00	Chu		
	AI	6,235,591	5/01	Balasubramanian		
DV	AJ	6,198,144 B1	3/01	Pan		
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FOREIGN PATENT DOCUMENTS						
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EXAMINER <i>gfuland</i>			DATE CONSIDERED 05/28/02			
<small>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>						



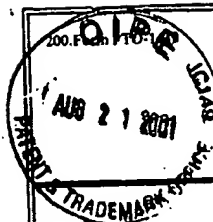
200 Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-1035		SERIAL NO. 09/234,233			
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				FILING DATE January 20, 1999		GROUP 2818			
U.S. PATENT DOCUMENTS									
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate			
DV	AA	5,376,591	12/27/94	Macda et al	—	—	—		
	AB	5,817,549	10/06/98	Yamazaki et al	—	—	—		
	AC	6,235,568 B1	5/01	Murthy	—	—	—		
	AD	6,187,694 B1	2/01	Cheng	—	—	—		
	AE	5,750,442	5/98	Juengling	—	—	—		
	AF	6,114,255	9/00	Juengling	—	—	—		
	AG	6,238,976	5/01	Noble	—	—	—		
	AH	6,008,121	12/99	Yang	—	—	—		
	AJ	5,140,390	8/92	Li	—	—	—		
	AJ	5,286,661	2/94	de Fresart	—	—	—		
	AK	6,184,151	2/01	Adair	—	—	—		
DV	AL	6,225,217 B1	5/01	Usami	—	—	—		
FOREIGN PATENT DOCUMENTS									
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		LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)					
		APPLICANT Weimin Li				FILING DATE January 20, 1999	
U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
DV	AA	6,087,267	07-2000	Dockery et al	—	—	—
	AB	5,543,654	08-1996	Dennen	—	—	—
	AC	5,656,330	08-1997	Niiyama et al	—	—	—
	AD	5,872,035	02-1999	Kim	—	—	—
	AE	4,444,617	04-1984	Whitcomb	—	—	—
	AF	6,071,799	06-2000	Park et al	—	—	—
	AG	5,691,212	11-1997	Tsai et al	—	—	—
	AH	6,187,657	02-2001	Xiang et al	—	—	—
	AI	5,792,689	08-1998	Yang et al	—	—	—
DV	AJ	2001/0023051	09-2001	Rolfson	—	—	—
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FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
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U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-1035		SERIAL NO. 09/234,233			
		APPLICANT Weimin Li		FILING DATE January 20, 1999			
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)							
U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
DV	AA	5,314,724	05/1994	Tsukane et al			
	AB	5,376,591	10/1998	Yamazaki et al			
	AC	6,001,741	12/1999	Alers			
	AD	6,072,227	06/2000	Yau et al			
	AE	5,786,039	7/1998	Brouquet			
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FOREIGN PATENT DOCUMENTS							
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OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)							
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EXAMINER <i>Shuland</i>				DATE CONSIDERED <i>10/11/01</i>			
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U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICE

ATTY. DOCKET NO.  
M122-1035

SERIAL NO.  
09/234,233

LIST OF ART CITED BY APPLICANT  
(Use several sheets if necessary)

APPLICANT  
Weimin Li

FILING DATE  
January 20, 1999

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U.S. PATENT DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
DV	AA	5,314,724	05/1994	Tsukane et al			
	AB	5,376,591	12-94 10/1996	Yamashita et al. Maeda et. al.			
	AC	6,001,741	12/1999	Alers			
	AD	6,072,227	06/2000	Yau et al			
	AE	5,786,039	7/1998	Brouquet			
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FOREIGN PATENT DOCUMENTS

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OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

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LIST OF ART CITED BY APPLICANT  
(Use several sheets if necessary)APPLICANT  
Weimla LJ et al.FILING DATE  
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## U.S. PATENT DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate
DV	AA	4,474,975	10/84	Clemons et al.			
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	AC						
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## FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AL							
	AM							
	AN							

## OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)

DV	AO	M. Matsura et al.; "A Highly Reliable Self-planarizing Low-k Intermetal Dielectric for Sub-quarter Micron Interconnects"; July 1997; pp. 31.6.1-31.6.4
DV	AP	O. Horie et al.; "Kinetics and Mechanism of the Reactions of O <sub>2</sub> P with SiH <sub>4</sub> , CH <sub>3</sub> SiH <sub>3</sub> , (CH <sub>3</sub> ) <sub>2</sub> SiH <sub>2</sub> , and (CH <sub>3</sub> ) <sub>3</sub> SiH"; The Journal of Physical Chemistry, Vol. 95, No. 11, 1991; pp. 4393-4400
DV	AQ	Robert Wilmall et al.; "Matrix Reactions of Methylsilanes and Oxygen Atoms"; The Journal of Physical Chemistry, Vol. 92, No. 3, 1988; pp. 594-602
DV	AR	Ajay M. Joshi et al.; "Plasma Deposited Organosilicon Hydride Network Polymers as Versatile Resists for Entirely Dry Mid-Deep UV Photolithography"; SPIE Vol. 1925, 1993; pp. 709-720

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DATE CONSIDERED

07/07/00

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Form PTO-1449		 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-1035		SERIAL NO. 09/234,233	
LIST OF REFERENCES CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Weimin Li			
FILING DATE January 20, 1999				GROUP 2818			
U.S. PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
DV	AA	5,585,880	1/1999	Dobson et al	—	—	—
	AB	5,219,613	6/1993	Fabry et al	—	—	—
	AC	5,270,267	12/1993	Quellet	—	—	—
	AD	5,541,445	7/1996	Quellet	—	—	—
	AE	6,022,404	2/2000	Ettlinger et al	—	—	—
	AF	5,709,741	1/1998	Akamastu et al	—	—	—
	AG	4,648,904	3/1987	Depasquale et al	—	—	—
	AH	4,158,717	6/1979	Nelson	—	—	—
	AI	5,667,015	9/1997	Harestad et al	—	—	—
	AJ	5,661,093	8/1997	Ravi et al	—	—	—
	AK	5,536,857	7/1996	Naula	—	—	—
	AL	4,695,859	9/1987	Guha et al	—	—	—
	AM	4,954,867	6/1990	Hosaka	—	—	—
	AN	5,441,797	8/1995	Hogan	—	—	—
	AO	5,710,067	1/1998	Foote	—	—	—
	AP	5,759,755	6/1998	Park et al	—	—	—
	AQ	5,838,052	11/1998	McTeer	—	—	—
DV	AR	5,883,011	4/1999	Lin et al	—	—	—
FOREIGN PATENT DOCUMENTS							
Document Number	Date	Country	Class	Subclass	Translation		
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DV	AS	406244172A	9/1994	Japan	—	✓	
DV	AT	593,727	10/1947	GB	—	✓	
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
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U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE LIST OF PATENTS CITED BY APPLICANT (Use separate sheets if necessary)					APPLICANT Weimin Li			
					FILING DATE January 20, 1999		GROUP 2818	

U.S. PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
DV	AA	5,883,011	4/1999	Li et al			
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	AC	5,783,493	7/1998	Yeh et al			
	AD	5,807,660	9/1998	Lin et al			
	AE	4,833,096	5/1989	Huang et al			
	AF	5,405,489	4/1995	Kim et al			
	AG	5,470,772	11/1995	Woo			
	AH	5,652,187	7/1997	Kim et al			
	AI	5,656,337	8/1997	Park et al			
	AJ	4,805,683	2/1989	Magdo et al			
	AK	5,874,367	2/1999	Dobson			
DV	AL						

FOREIGN PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Country	Class	Subclass	Translation	
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DV	AM	06067019A	9/1999	Japan (Glass)			✓
DV	AN	9750993	2/1997	Japan			✓
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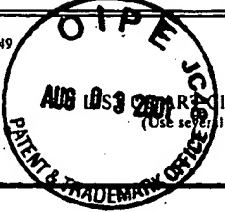
  

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)		
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DV	AO	TEXT: Wolf, S. et al., "Silicon Processing for the VLSI Era", Vol. 1, pp. 437-441. (No date)
	AR	

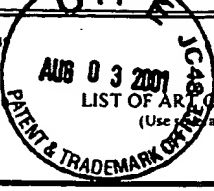
  

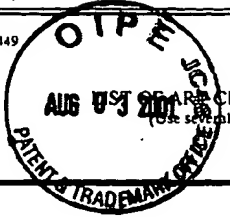
EXAMINER <i>Shuland</i>	DATE CONSIDERED 10/11/01
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APPLICANT Weimin Li						FILING DATE January 20, 1999		GROUP 2818	
U.S. PATENT DOCUMENTS									
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate			
DV	AA	5,061,509	10/1991	Naito et al					
	AB	4,600,671	7/1986	Saitoh et al					
	AC	5,753,320	5/1998	Mikoshiba et al					
	AD	5,356,515	10/1994	Tahara et al					
	AE	5,674,356	10/07/97	Nagayama					
	AF	5,731,242	03/24/98	Parat et al.					
	AG	5,741,721	04/21/98	Stevens					
	AH	5,034,348	07/23/91	Hartswick et al.					
	AI	5,472,829	12/05/95	Ogawa					
	AJ	5,641,607	06/24/97	Ogawa et al.					
DV	AK	5,648,202	07/15/97	Ogawa et al.					
	AL								
FOREIGN PATENT DOCUMENTS									
	Document Number	Date	Country	Class	Subclass	Translation			
						Yes	No		
DV	AM	5-263255	10/1993	Japan					
DV	AN	0 471 185 A2	7/10/91	EPO					
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)									
DV	AO	D.R. McKenzie et al., "New Technology for PACVD", Surface and Coatings Technology, 82 (1996), pp. 326-333.							
DV	AP	S. McClatchie et al.; "Low Dielectric Constant Flowfill® Technology For IMD Applications"; undated; 7 pages							
DV	AQ	K. Beekmann et al.; "Sub-micron Gap Fill and In-Situ Planarisation using Flowfill™ Technology"; October 1995; pp. 1-7							
EXAMINER				DATE CONSIDERED					
Huland				10/11/01					
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				FILING DATE January 20, 1999		GROUP 2818		
U.S. PATENT DOCUMENTS								
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
DV	AA	5,670,297	09/23/97	Ogawa et al.				
	AB	5,677,111	10/14/97	Ogawa				
	AC	5,698,352	12/16/97	Ogawa et al.				
	AD	5,831,321	11/03/98	Nagayama				
	AE	5,591,566	01/07/97	Ogawa				
	AF	6,008,124	12/28/99	Sekiguchi et al.				
	AG	5,340,621	08/23/94	Matsumoto et al.				
	AH	5,600,165	02/04/97	Tsukamoto et al.				
	AI	5,872,385	02/16/99	Taft et al.				
	AJ	5,960,289	09/28/99	Tsui et al.				
	AK	5,968,324	10/19/99	Cheung et al.				
DV	AL	6,020,243	02/01/00	Wallace et al.				
FOREIGN PATENT DOCUMENTS								
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DV	AM	0 588 087 A2	8/18/93	EPO				✓
DV	AN	0 588 087 A3	8/18/93	EPO				✓
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)								
DV	AO	A. Kiermasz et al.; "Planarisation for Sub-Micron Devices Utilising a New Chemistry"; Electrotech, February 1995; 2 pages						
DV	AP	IBM Technical Disclosure Bulletin "Low-Temperature Deposition of SiO <sub>2</sub> , Si <sub>3</sub> N <sub>4</sub> or SiO <sub>2</sub> -Si <sub>3</sub> N <sub>4</sub> ," Vol. 28, No. 9, p. 4170, Feb. 1986.						
DV	AQ	ARTICLE: Bencher, C. et al., "Dielectric antireflective coatings for DUV lithography", Solid State Technology (March 1997), pp.109-114.						
EXAMINER				DATE CONSIDERED				
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								

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ARE CITED BY APPLICANT <small>(Use several sheets if necessary)</small>						APPLICANT Weimin Li			
FILING DATE January 20, 1999						GROUP 2818			

U.S. PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
DV	AA	6,054,379	04/25/00	Yau et al.			
	AB	5,948,482	09/07/99	Brinker et al.			
	AC	5,800,877	09/01/98	Maeda et al.			
	AD	5,260,600	11/09/93	Harada			
	AE	4,992,306	02/12/91	Hochberg et al.			
	AF	4,702,936	10/27/87	Maeda et al.			
	AG	4,863,755	09/05/89	Hess et al.			
	AH	5,234,869	08/10/93	Mikata et al.			
	AI	5,302,366	04/12/94	Schuetz et al.			
	AJ	5,591,494	01/07/97	Sato et al.			
	AK	5,968,611	10/19/99	Kaloyeros et al.			
	AL	6,159,871	12/12/00	Loboda et al.			
	AM	5,744,399	4/1998	Rostoker			
	AN	5,883,014	3/1999	Chen			
DV	AO	6,017,779	1/25/00	Miyasaka			

FOREIGN PATENT DOCUMENTS							
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DV	AP	09055351	25/2/97	Japan			✓
DV	AQ	0 778 496 A2	05/12/96	EPO			✓

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)			
DV	AR		Noboru Shibata, "Plasma-Chemical Vapor-Deposited Silicon Oxide/Silicon Oxynitride Double-Layer Antireflective Coating for Solar Cells", Japanese Journal of Applied Physics, Vol. 30, No. 5, May 1991, pp. 997-1001.
DV	AS		Julius Grant, Hack's Chemical Dictionary, Fourth Edition, McGraw-Hill Book Company, © 1969, rented by Grant © 1972, pp. 27.

EXAMINER <i>Stuland</i>	DATE CONSIDERED <i>10/11/01</i>
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				FILING DATE January 20, 1999		GROUP 2818			
U.S. PATENT DOCUMENTS									
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DV	AA	5,472,827	12/1995	Ogawa et al.	—	—	—		
	AB	6,156,674	12/5/00	Li et al	—	—	—		
	AC	6,461,003	10/24/95	Haveman	—	—	—		
	AD	6,124,641	9/26/00	Matsura	—	—	—		
↓	AE	5,554,567	9/10/96	Wang	—	—	—		
DV	AF	6,028,015	2/22/00	Wang	—	—	—		
FOREIGN PATENT DOCUMENTS									
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						Yes	No		
DV	AG	EP 0 464 515 A3/B1	08.01.92	EPO (Mikata et al.)	—	—	✓		
DV	AH	EP 0 771 886 A1	07.05.97	EPO (Loboda)	—	—	✓		
DV	AI	20029	US99	Search Report	—	—	✓		
DV	AJ	20030	US99	Search Report	—	—	✓		
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)									
DV	AK	Ralls, Kenneth M., "Introduction to Materials Science and Engineering", John Wiley & Sons, © 1976, pp. 312-313							
DV	AL	Ravi K. Laxan, "Synthesizing Low-k CVD Materials for Fab Use", Semiconductor International, Nov. 2000, 10 pps.							
DV	AM	Anonymous, "New gas helps make faster IC's, Machine Design Cleveland, © Penton Media, Inc., November 4, 1999, pp. 118							
DV	AN	Lobada et al, "Using Trimethylsilane to Improve Safety Throughput and Versatility in PECVD Processes", 4th International Symposium on Silicon Nitride and Silicon Dioxide Thin Insulating Films, The Electrochemical Society, Abstract No. 358, p. 454, May 1997.							
DV	AO	ARTICLE: Bencher, C. et al., "Dielectric antireflective coatings for DUV lithography", Solid State Technology (March 1997), pp. 109-114.							
DV	AP	ARTICLE: Dammel, R. R. et al., "Dependence of Optical Constants of AZ® BARLi™ Bottom Coating on Back Conditions", SPIE Vol. 3049 (1997), pp. 963-973.							
DV	AQ	TEXT: Heavens, O. S., "Optical Properties of Thin Solid Films", pp. 48-49.							
EXAMINER <i>Grubel</i>				DATE CONSIDERED <i>10/11/01</i>					
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.									

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<div style="display: inline-block; border: 2px solid black; border-radius: 50%; padding: 10px; text-align: center;"> <b>OIPF</b>          LIST OF ARTS CITED BY APPLICANT          AUG 03 2001          (see sheets if necessary)          PATENT &amp; TRADEMARK OFFICE       </div>					APPLICANT Weimin Li			
					FILING DATE January 20, 1999		GROUP 2818	
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DV	AA	09/146,842	9/3/98	Yin et al				
DV	AB	09/146,843	9/3/98	Li et al				
DV	AC	09/030,618	2/25/98	Holscher et al				
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EXAMINER <i>grifland</i>					DATE CONSIDERED <i>10/11/01</i>			
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PATENT AND TRADEMARK OFFICE

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M22-1035

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APPLICANT  
Weimin Li

FILING DATE  
January 20, 1999

GROUP  
2818

U.S. PATENT DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
DV	AA	6,184,158	02/2002	Shufflebotham et al			
	AB	6,096,656	08/2000	Matzke et al			
	AC	6,209,484	04/2001	Huang et al			
	AD	6,440,860	08/2002	DeBoer et al			
	AE	5,413,963	05/1995	Yen et al			
	AF	6,143,670	11/2000	Cheng et al			
	AG	6,403,464	06/2002	Chang			
	AH	2001/0038919 A1	11/2001	Berry, III et al			
	AI	2002/0033486 A1	03/2002	Kim et al			
DV	AJ	2002/0081834 A1	06/2002	Daniels et al			
	AK						
	AL						

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
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DV	AM	EP 1172845 A2	01/2002	EP				✓
	AN	JP 08-213386 A	08/1996	JP				✓
	AO	JP 2000068261 A	03/2000	JP				✓
	AP	TW 368687 A	09/1999	TW				✓
	AQ	TW 429473 A	04/2001	TW				✓
DV	AR	TW 420844 A	02/2001	TW				✓

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

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DATE CONSIDERED 01/15/03

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Sheet 1 of 1

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LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Weimin Li	
				FILING DATE January 20, 1999	GROUP 2818

U.S. PATENT DOCUMENTS							
*Examiner Initial	Class	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
Dh	AA	6,121,133	09/2000	Iyer et al			
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

FOREIGN PATENT DOCUMENTS							
Class	Subclass	Document Number	Date	Country	Class	Subclass	Translation
		AL					Yes No
		AM					
		AN					

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)			
Dh	AO	Wolf et al, Silicon Processing for the VLSI Era, 1986, Lattice Press, Vol. 1, pp. 1 and 2.	
	AP		
	AO		

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LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Weimin Li			
				FILING DATE January 20, 1999		GROUP 2510	

U.S. PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
Dle	AA	6368282	07/2001	Sandhu et al			
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	AC						
	AD						
	AE						
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	AG						
	AH						
	AI						
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	AK						

FOREIGN PATENT DOCUMENTS							
	Document Number	Date	Country	Class	Subclass	Translation	
						Yes	No
	AL						
	AM						
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OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)			
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